

## **KETEK GmbH Munich - Germany**

# Silicon Sensors realized by KETEK

- Short Product Overview -

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## **KETEK** at a Glance

- Medium size, family-owned enterprise
- Number of employees: 55
- Company based in Munich, Germany
- Major product lines:SDD-Modules, Detector Electronics, Complete Systems
- New product:
  SiPM-Modules







## **KETEK SDD X-Ray Detectors**

#### **KETEK Silicon Drift Detectors** X-ray detectors for XRF, TXRF, EDX

- Sizes from 7 100 mm² active area
- Energy resolutions down to **121eV** (Mn  $K\alpha$ )
- Peak to Background > 10.000
- Vacuum types with high thermal budget: ΔT>75K
- No detector fluorescence lines
- State of the art product in the analytic market

#### VITUS H<sub>30</sub>

40mm<sup>2</sup> SDD chip; 30mm<sup>2</sup> active area; multi-layer collimator; **8µm Be window** 



VITUS H50

65mm<sup>2</sup> SDD chip; 50mm<sup>2</sup> active area; multi-layer collimator; **12.5µm Be window** 







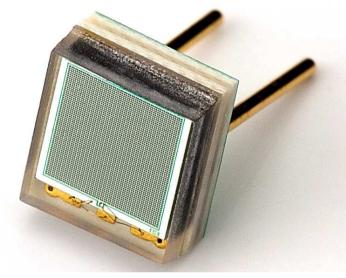
# **KETEK SiPM Low Level Light Sensors**

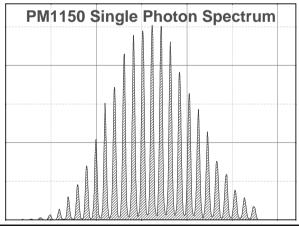
#### **KETEK Silicon Photomultipliers**

- Fast Single Photon Counting -
- High PDE up to **60** % for 50µm cell type
- Optimized for blue light sensitivity
- Low dark rate and low cross talk
- Huge bias voltage range of stable operation
- Extremely low temperature coefficient

#### PM3350

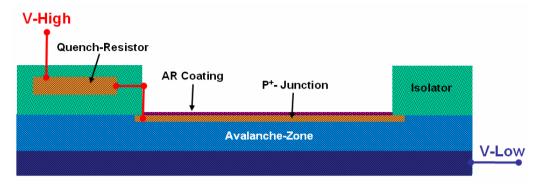
3 x 3mm<sup>2</sup> active area; 50 µm microcell type; peak wavelength 420 nm; plastic package





## **Basic Construction of the KETEK Microcell**

#### **Section of KETEK Basic Microcell**



- Silicon P on N structure with high Geiger efficiency
- Shallow entrance window with high quantum efficiency
- Optimized geometrical fill factor
- ⇒ High photon detection efficiency

- Available in two technologies -

## **KETEK Standard Technology**

- Technology optimized for maximum GE
- Devices with very high PDE
- Particularly suitable for small microcells and small active area

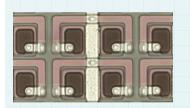
#### **KETEK Trench Technology**

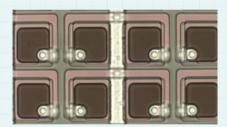
- Technology with improved optical barrier and low-RC readout
- Devices with low crosstalk and improved timing
- Particularly suitable for large microcells and large area devices



## **KETEK SiPM Microcell Sizes**

- Microcell sizes from 15µm up to 100µm realized
- Geometrical efficiency up to 75% (depending on microcell size)
- Standard type: 50µm











15 μm GE 30% 20 μm GE 40% 50 μm GE 60% 60 μm GE 68% 100 μm GE 75%

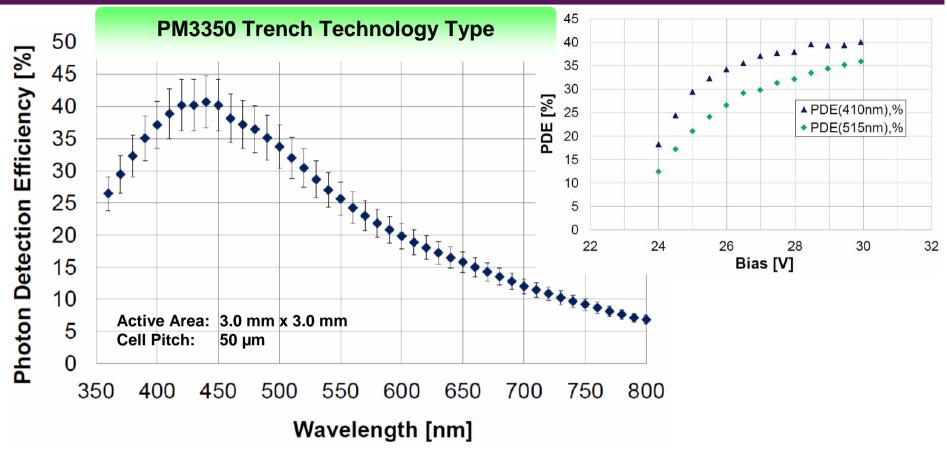
**High Dynamic Detection Range** 

**High Photon Detection Efficiency** 



## **Photo Detection Efficiency measured at CERN**

## (PM3350 Trench Type)

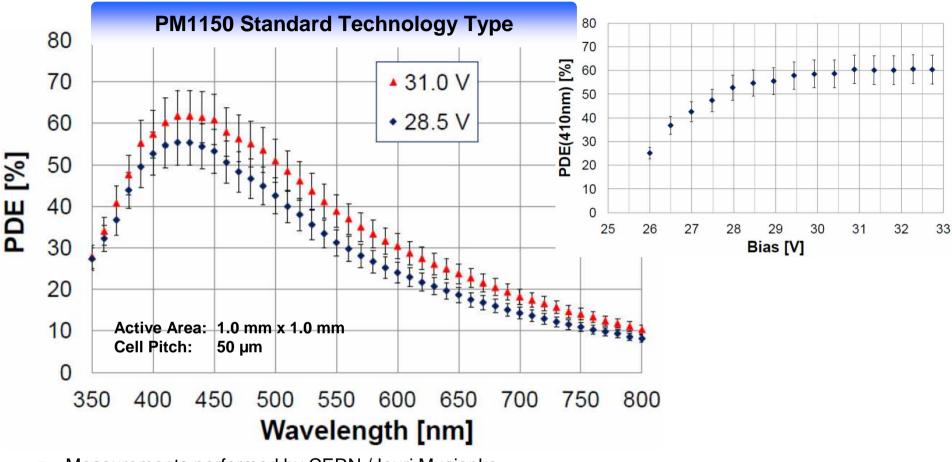


- Measurements performed by CERN / Iouri Musienko
- PDE is not affected by crosstalk and afterpulsing
- Optimized for blue light sensitivity
- 40% PDE for blue light



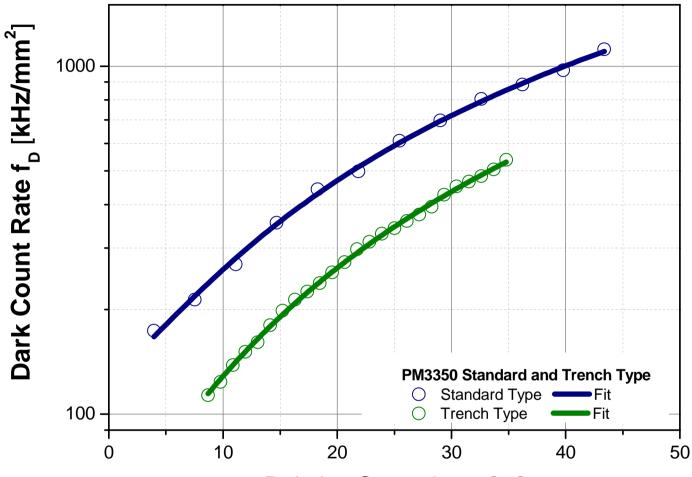
## **Photo Detection Efficiency measured at CERN**

## (PM1150 Standard Type)



- Measurements performed by CERN / Iouri Musienko
- PDE is not affected by crosstalk and afterpulsing
- Optimized for blue light sensitivity
- 60% PDE for blue light



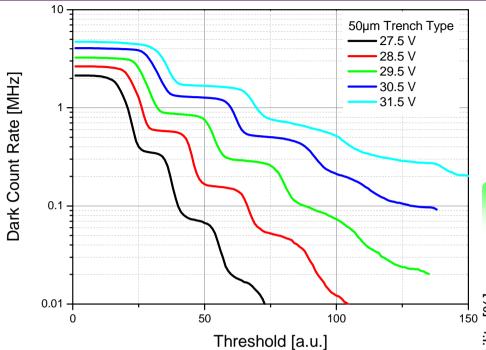


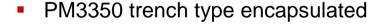
Dark count rate at 20% overvoltage

Relative Overvoltage [%]

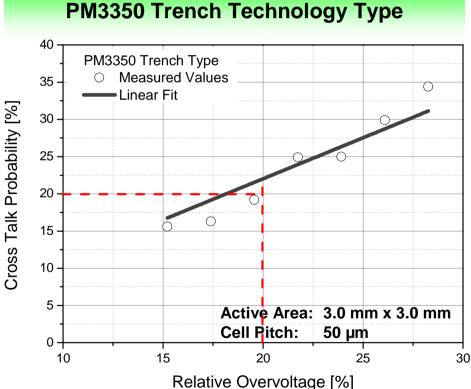
- standard technology ≤ 500 kHz/mm²
- trench technology ≤ 300 kHz/mm²





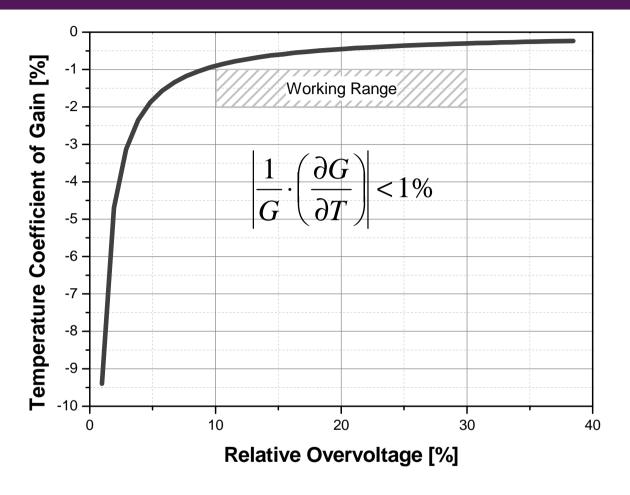


- Crosstalk evaluation based on dark rate versus threshold measurement
- 20% crosstalk probability at 20% overvoltage





## **Temperature Coefficient of the Gain**



- Low temperature coefficient of break down voltage (~ 22 mV/℃)
- Operation at high overvoltage (~ 20%)
- ⇒ Low temperature coefficient of gain (<1%)



# Scheduled Portfolio - Completely Available until End 2012

	Active Area [mm]	Cell Pitch [µm]	Standard	Trench
PM11 SMD	1.2 × 1.2	50 μm	Х	Х
	1.2 × 1.2	75 µm		Х
	1.2 x 1.2	100 µm		Χ
PM22 SMD	2.0 x 2.0	50 μm	Х	Х
	2.0 × 2.0	100 µm		Х
PM33 Pin SMD	3.0 × 3.0	50 μm	Х	Х
	3.0 × 3.0	60 µm	Χ	X
	3.0 x 3.0	75 µm	Χ	Χ
PM66 - Pin	6.0 × 6.0	60 µm		Х

#### PM3350 - Pin

3 x 3mm² active area; 50 µm cell type; peak wavelength 420 nm; plastic package



